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** CONTINUING DATA *****

MK (verified)

** FOREIGN APPLICATIONS *****

JAPAN 2002-259579 09/05/2002

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IF REQUIRED, FOREIGN FILING LICENSE GRANTED

** 11/21/2003

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|---------------------------------|--|----------|---------|--------|-------------|
| Foreign Priority claimed | <input checked="" type="checkbox"/> yes <input type="checkbox"/> no | STATE OR | SHEETS | TOTAL | INDEPENDENT |
| 35 USC 119 (a-d) conditions met | <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance | COUNTRY | DRAWING | CLAIMS | CLAIMS |
| Verified and Acknowledged | <i>MK</i> Examiner's Signature Initials | JAPAN | 7 | 4 | 1 |

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TITLE

Silicon wafer cleaning method